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**EE C245 - ME C218**  
**Introduction to MEMS Design**  
**Fall 2010**

**Prof. Clark T.-C. Nguyen**

Dept. of Electrical Engineering & Computer Sciences  
University of California at Berkeley  
Berkeley, CA 94720

**Lecture Module 9: Energy Methods**

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**Lecture Outline**

- Reading: Senturia, Chpt. 10
- Lecture Topics:
  - ↳ Energy Methods
    - ↳ Virtual Work
    - ↳ Energy Formulations
    - ↳ Tapered Beam Example

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## Energy Methods

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## More General Geometries

- Euler-Bernoulli beam theory works well for simple geometries
- But how can we handle more complicated ones?
- Example: tapered cantilever beam
- Objective: Find an expression for displacement as a function of location  $x$  under a point load  $F$  applied at the tip of the free end of a cantilever with tapered width  $W(x)$

Top view of cantilever's  $W(x)$

$W(x) = W\left(1 - \frac{x}{2L_c}\right)$

50% taper

$x = L_c$

$F$

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**Solution: Use Principle of Virtual Work**

- In an energy-conserving system (i.e., elastic materials), the energy stored in a body due to the quasi-static (i.e., slow) action of surface and body forces is equal to the work done by these forces ...
- Implication:** if we can formulate **stored energy** as a function of the deformation of a mechanical object, then we can determine how an object responds to a force by determining the shape the object must take in order to **minimize** the **difference U** between the stored energy and the work done by the forces:

$$U = \text{Stored Energy} - \text{Work Done}$$

- Key idea:** we don't have to reach  $U = 0$  to produce a very useful, approximate *analytical* result for load-deflection

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**More Visual Description ...**

Same problem as before: Take a beam & apply a force:

- Apply force.
- Beam responds by bending.
- This force has done work:  $W = F \cdot y(L_c)$
- Strain generated → This means the beam has received an influx of stored energy

⑤ Then:  
 $U = \text{Stored Energy} - \text{Work Done} \rightarrow 0$   
 (When we choose the right shape! (This is how we get the beam's response to F!))

magnitude determined by its deformed shape

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**Fundamentals: Energy Density**

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- Strain energy density: [J/m<sup>3</sup>]  $w(Q) = \int_0^Q \frac{Q}{C} dQ \rightarrow$  charging a capacitor from 0  $\rightarrow$  Q takes this much work stored energy on a capacitor
- ↳ To find work done in straining material

This is a definition, so really can just say it's a definition.

$$w = \int_0^{\epsilon_x} \sigma_x d\epsilon_x \quad \text{x-axis normal stress term}$$

$\sigma_x(\epsilon_x) \rightarrow$  relates stress to strain @ position (x, y, z)  
 value of strain @ position (x, y, z)

$$[\sigma_x = E\epsilon_x] \Rightarrow w = \int_0^{\epsilon_x} E\epsilon_x d\epsilon_x = \frac{1}{2} E\epsilon_x^2$$

$w(q) = \int_0^q e(q) dq$   $q =$  displacement } Generic Definition of Work  
 $e =$  effort

- Total strain energy [J]:
- ↳ Integrate over all strains (normal and shear)

$$W = \iiint \left( \frac{1}{2} E(\epsilon_x^2 + \epsilon_y^2 + \epsilon_z^2) + \frac{1}{2} G(\gamma_{xy}^2 + \gamma_{yz}^2 + \gamma_{zx}^2) \right) dV$$

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**Bending Energy Density**

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Neutral Axis  
 $y(x) =$  transverse displacement of neutral axis

- First, find the bending energy  $dW_{\text{bend}}$  in an infinitesimal length  $dx$ :  $W =$  width

$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \epsilon_x^2(y') dy'$$

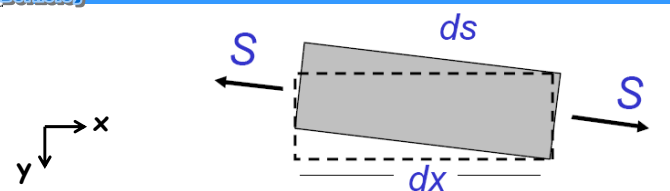
$$\left[ \frac{1}{R} = \frac{d^2 y}{dx^2}, \epsilon_x = \frac{y'}{R} \right] \Rightarrow \epsilon_x(y') = y' \frac{d^2 y}{dx^2}$$

$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \left[ y' \frac{d^2 y}{dx^2} \right]^2 dy' = \frac{1}{2} E \left( \frac{Wh^3}{12} \right) \left( \frac{d^2 y}{dx^2} \right)^2 dx$$

$$\therefore W_{\text{bend}} = \frac{1}{2} E I_z \int_0^L \left( \frac{d^2 y}{dx^2} \right)^2 dx$$

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**Energy Due to Axial Load**




• Strain due to axial load  $S$  contributes an energy  $dW_{\text{stretch}}$  in length  $dx$ , since lengthening of the different element  $dx$  (to  $ds$ ) results in a strain  $\epsilon_x$

$ds = [(dx)^2 + (dy)^2]^{1/2} = dx \left[ 1 + \left( \frac{dy}{dx} \right)^2 \right]^{1/2} \xrightarrow{\text{Binomial Theorem}} dx \left[ 1 + \frac{1}{2} \left( \frac{dy}{dx} \right)^2 \right]$   
 $\therefore \epsilon_x = \frac{ds - dx}{dx} = \frac{1}{2} \left( \frac{dy}{dx} \right)^2$   
 $\left[ dW_{\text{axial}} = S \epsilon_x dx = \frac{1}{2} S \left( \frac{dy}{dx} \right)^2 dx \right] \Rightarrow \boxed{W_{\text{axial}} = \frac{1}{2} S \int_0^L \left( \frac{dy}{dx} \right)^2 dx}$

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**Shear Strain Energy**



$$W_{\text{shear}} = \frac{3(EI_z)^2}{4GWh} \int_0^L \left( \frac{d^3 y}{dx^3} \right)^2 dx$$

Shear Modulus

• See W.C. Albert, "Vibrating Quartz Crystal Beam Accelerometer," Proc. ISA Int. Instrumentation Symp., May 1982, pp. 33-44

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**Applying the Principle of Virtual Work**

- **Basic Procedure:**
  - ↪ Guess the form of the beam deflection under the applied loads
  - ↪ Vary the parameters in the beam deflection function in order to minimize:

$$U = \sum_j W_j - \sum_i F_i u_i$$

Sum strain energies (bracketed over the first sum)  
 Assumes point load (arrow pointing to  $F_i$ )  
 Displacement at point load (arrow pointing to  $u_i$ )

- ↪ Find minima by simply setting derivatives to zero
- See Senturia, pg. 244, for a general expression with distributed surface loads and body forces

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**Example: Tapered Cantilever Beam**

- **Objective:** Find an expression for displacement as a function of location  $x$  under a point load  $F$  applied at the tip of the free end of a cantilever with tapered width  $W(x)$

Top view of cantilever's  $W(x)$

$W(x) = W(1 - \frac{x}{2L_c})$

50% taper

$x = L_0$

Adjustable parameters: minimize  $U$

$y(x) = c_2 x^2 + c_3 x^3$

- Start by guessing the solution
  - ↪ It should satisfy the boundary conditions
  - ↪ The strain energy integrals shouldn't be too tedious
    - This might not matter much these days, though, since one could just use matlab or mathematica

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**Strain Energy And Work By F**

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$$U = \mathcal{W}_{bend} - F \cdot y(L_c)$$

$$\mathcal{W}_{bend} = \frac{1}{2} E \int_0^{L_c} I_z(x) \left( \frac{d^2 y}{dx^2} \right)^2 dx \quad (\text{Bending Energy})$$

$$I_z(x) = \frac{W(x)h^3}{12}$$

$$W(x) = W \left( 1 - \frac{x}{2L_c} \right)$$

$$\frac{d^2 y}{dx^2} = 2c_2 + 6c_3 x \quad (\text{Using our guess})$$

Tip Deflection

$$= \frac{1}{24} E W h^3 \int_0^{L_c} \left( 1 - \frac{x}{2L_c} \right) (2c_2 + 6c_3 x)^2 dx - F(c_2 L_c^2 + c_3 L_c^3)$$

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**Find  $c_2$  and  $c_3$  That Minimize  $U$**

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- Minimize  $U \rightarrow$  basically, find the  $c_2$  and  $c_3$  that brings  $U$  closest to zero (which is what it would be if we had guessed correctly)
- The  $c_2$  and  $c_3$  that minimize  $U$  are the ones for which the partial derivatives of  $U$  with respect to them are zero:

$$\frac{\partial U}{\partial c_2} = 0 \qquad \frac{\partial U}{\partial c_3} = 0$$

- Proceed:
  - First, evaluate the integral to get an expression for  $U$ :

$$U = E W h^3 \left\{ \frac{5c_3^2}{16} L_c^3 + \frac{c_2 c_3}{3} L_c^2 + \frac{c_2^2}{8} L_c \right\} - F(c_2 L_c^2 + c_3 L_c^3)$$

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## Minimize U (cont)

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- Evaluate the derivatives and set to zero:


$$\frac{\partial U}{\partial c_2} = 0 = \left( \frac{EWh^3}{3} c_3 - F \right) L_c^2 + \left( \frac{EWh^3}{4} c_2 \right) L_c$$

$$\frac{\partial U}{\partial c_3} = 0 = \left( \frac{5}{8} EWh^3 c_3 - F \right) L_c^3 + \left( \frac{EWh^3}{3} c_2 \right) L_c^2$$

- Solve the simultaneous equations to get  $c_2$  and  $c_3$ :

$$c_2 = \left( \frac{84}{13} \right) \frac{FL_c}{EWh^3} \quad c_3 = - \left( \frac{24}{13} \right) \frac{F}{EWh^3}$$

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## The Virtual Work-Derived Solution

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- And the solution:

$$y(x) = \left( \frac{24F}{13EWh^3} \right) \left( \left( \frac{7}{2} \right) L_c - x \right) x^2$$

- Solve for tip deflection and obtain the spring constant:

$$y(L_c) = \left( \frac{24F}{13EWh^3} \right) \left( \frac{5}{2} \right) L_c^3 \quad k_c = F / y(L_c) = \left( \frac{13EWh^3}{60L_c^3} \right)$$

- Compare with previous solution for constant-width cantilever beam (using Euler theory):

$$y(L_c) = \left( \frac{4F}{EWh^3} \right) L_c^3 \longrightarrow \text{13\% smaller than tapered-width case}$$

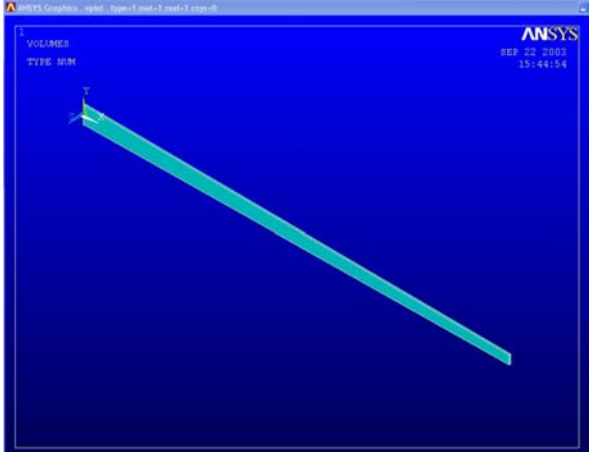
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### Comparison With Finite Element Simulation

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- Below: ANSYS finite element model with
  - $L = 500 \mu\text{m}$     $W_{\text{base}} = 20 \mu\text{m}$     $E = 170 \text{ GPa}$
  - $h = 2 \mu\text{m}$     $W_{\text{tip}} = 10 \mu\text{m}$



The image shows a screenshot of the ANSYS software interface. It displays a 3D model of a cantilever beam, colored in a light blue/cyan hue, against a dark blue background. The beam is fixed at one end and extends diagonally. The ANSYS logo and some system information (SEP 22 2003 15:44:54) are visible in the top right corner of the window.

- Result: (from static analysis)
  - $k = 0.471 \mu\text{N/m}$
- This matches the result from energy minimization to 3 significant figures

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### Need a Better Approximation?

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- Add more terms to the polynomial
- Add other strain energy terms:
  - Shear: more significant as the beam gets shorter
  - Axial: more significant as deflections become larger
- Both of the above remedies make the math more complex, so encourage the use of math software, such as Mathematica, Matlab, or Maple
- Finite element analysis is really just energy minimization
- If this is the case, then why ever use energy minimization analytically (i.e., by hand)?
  - Analytical expressions, even approximate ones, give insight into parameter dependencies that FEA cannot
  - Can compare the importance of different terms
  - Should use in tandem with FEA for design

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